

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Grimbergen, et al.	Group Art Unit: 1763
Serial No: 09/667,362	Examiner: Unknown
Confirmation No: 9755	Attorney Docket No: 002813 USA P01/ETCH/SILICON/JB
Filed: Sep 21, 2000	November 27, 2001 San Francisco, California
Title: REDUCING DEPOSITION OF PROCESS RESIDUE ON A WINDOW OF A CHAMBER	

SUBMISSION OF FORMAL DRAWINGS

Commissioner of Patents and Trademarks  
Washington, D.C. 20231

Attention: Official Draftsperson

Sir:

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Enclosed are sixteen (16) sheets of formal drawings for the above-identified application .

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

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By

*Rowena Montoya*  
Rowena Montoya


Dated

*11/27/2001*

It is believed that no fee or petition is associated with this communication. If, however, any fee or petition is due, Applicant hereby petitions the Commissioner for the same, and authorizes the Commissioner to charge payment of any fees associated with this communication to Deposit Account No. 10-0258. A duplicate copy of this sheet is enclosed.

Respectfully submitted,  
JANAH & ASSOCIATES  
A PROFESSIONAL CORPORATION

Dated: November 27, 2001

By:   
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